

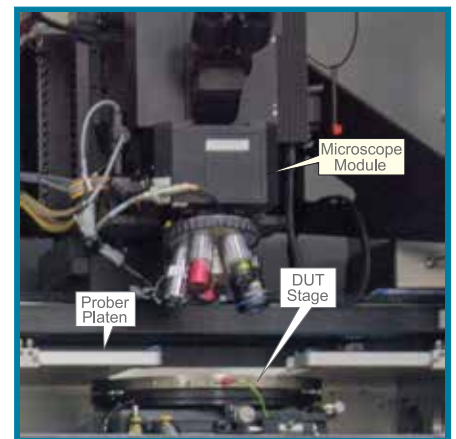
SEMICAPS 1100

UPRIGHT ANALYTICAL SYSTEM



Features

- For backside and frontside analysis of wafers, wafer parts and packaged devices
- Ultra-stable system compatible for probing FIB pads
- Compatible with third-party probe stations, probe cards and manipulators
- High resolution stage with 0.5 μm repeatability
- Centric and Aplanatic Refractive Solid Immersion Lens (RSIL) option
- CAD interface option
- Compatible with thermal management solutions
- Techniques include a combination of:
 - Laser Timing Probe (LTP)
 - Scanning Optical Microscopy (SOM) with best sensitivity
 - static: TIVA, OBIRCH
 - dynamic: LADA, SDL
 - Photon Emission Microscopy (PEM) with various options for the InGaAs or Si-CCD camera
 - Thermal Microscopy (THM) with InSb camera



300 mm Probe Station